

II. CLAIM AMENDMENTS

1. (Currently Amended) A detection/cleaning device for reticles employed in the production of electronic components, wherein the detection/cleaning device has a closable housing capable of holding a controlled atmosphere therein; a cleaning unit, inside the closable housing and in which a cleaning chamber is constructed, at least one gas feed for introducing a pressurized fluid cleaning medium opens into the cleaning chamber, and at least one suction ~~means~~, by means of through which the gas can be discharged from the cleaning chamber, leads from the cleaning chamber, wherein the cleaning chamber has at least one first opening for introducing and removing a reticle,

is further provided with a detection unit for detecting contaminants on articles used in semiconductor production, wherein, to this end, the detection unit has a detection ~~means~~device, into which a reticle can be introduced from one feed side of the detection unit, wherein the first opening of the cleaning chamber and the feed side lie on opposite sides of the cleaning chamber from each other, and

is provided with a feeding device, which is provided solely for exchanging a reticle between the cleaning unit and the detection unit.

2. (Original) The detection/cleaning device according to claim 1, in which the feeding device is provided with only one axis of movement.

3. (Original) The detection/cleaning device according to claim 2, in which the feeding device is provided with only one axis of linear travel.

4. (Original) The detection/cleaning device according to claim 1, further characterized in that an opening is provided for the cleaning chamber on each of the opposite-lying sides, wherein a reticle can be introduced into the cleaning chamber through both openings by input and output.

5. (Original) The detection/cleaning device according to claim 4, further characterized in that one of the openings lies directly opposite a recess of the housing of the detection unit for feeding in a reticle.

6. (Original) The detection/cleaning device according to claim 1, further characterized in that the feeding device has a movable holding part in which a reticle can be arranged in a clamp and the reticle can be introduced into both the detection unit and the cleaning chamber in only this one clamp.

7. (new) A substrate processing apparatus comprising:

a housing arranged so that the housing is capable of holding an isolated atmosphere isolated from an exterior atmosphere outside the housing;

a reticle cleaning device connected to and located in the housing, the cleaning device having a reticle cleaning chamber defined therein and an opening through which a reticle is transported in and out of the cleaning chamber;

a detection device connected to and located in the housing, the detection device being adapted to detect contaminants on the reticle; and

a transport device movably connected to and located in the housing, the transport device being capable of transporting

the reticle between the reticle cleaning device and the detection device;

wherein the reticle cleaning device and the detection device are arranged so that the transport device feeds the reticle into the detection device through the opening of the cleaning device.